



Appl. No.: 10/733,009
Amdt. Dated: July 30, 2004
Reply to Office Action of: May 10, 2004

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appl. No. : 10/733,009
Applicant : Berkey, et al.
Filed : December 10, 2003
Title : PROJECTION LITHOGRAPHY PHOTOMASKS AND METHOD
OF MAKING


TC/A.U. : 1756
Examiner : Rosasco, Stephen

Docket No. : Berkey 47B

Mail Stop: Amendments
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

CERTIFICATE OF MAILING (37 CFR 1.8a)

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Signature

RESPONSE TO THE EXAMINER'S OFFICE ACTION

Sir:

In response to the Office action of May 10, 2004, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 5 of this paper.